



Discussion on LEM design for phase II of ProtoDUNE-DP

What are the ways of improvements ?

1/ the LEM itself (design/manufacturing)

- ❑ LEM parameters : increase thickness, decrease number of holes ? Other parameters to optimize ? RIM ? Different size on the 2 sides ?
- ❑ Global quality of holes' drilling & RIM etching locally affecting electric field
 - With a 40 μm RIM, can an even more smooth RIM edge help ?
 - Improve RIM etching (etching defects for holes on borders and corners)
 - Other improvement in the manufacturing procedure ?
 - Covering of the RIM copper edges with an insulating layer
 - How to set-up the burn-in procedure to remove residual copper asperities ?
- ❑ Electric field increase on LEM borders & in the holes close to the borders/corners
 - Larger holes on the first few rows of holes from the border ?
 - LEM active area segmentation ?
 - Optimize the FR4 & copper guard rings dimensions on borders/corners
 - Covering of the copper edges with an insulator layer
- ❑ Other ideas ? Resistive LEM, resistive anode, multi-LEM, LEM with internal shaping electrodes...

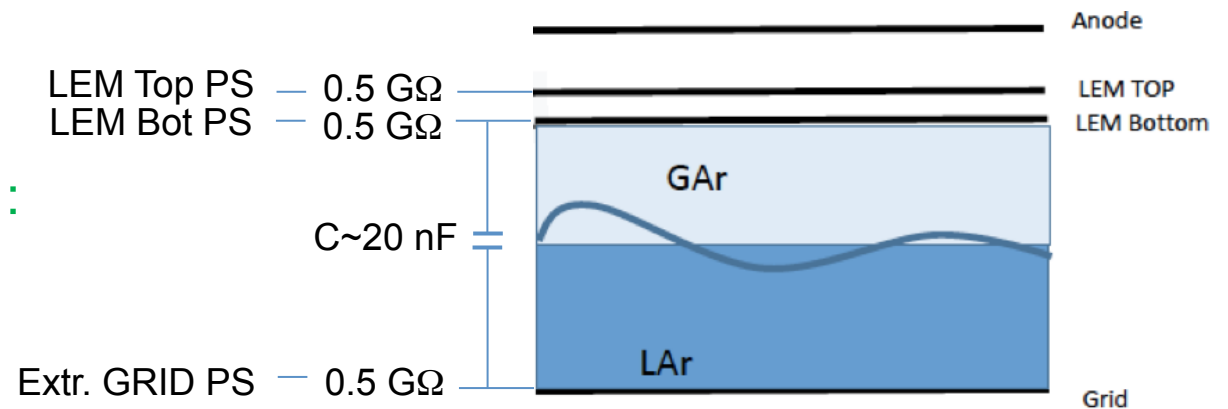
→ The R&D requires testing long term operation stability & ageing, both with individual LEMs in laboratory (3,3 bar argon) and with large area (> 4 LEMs) in DLA conditions (« cold box »)

What are the ways of improvements ?

2/ the LEM operation conditions

- Disentangle LEMs stability from instabilities (LEM ΔV) related to the capacitive coupling (depending on liquid surface stability) between the LEM bottom side and the extraction grid :

→ improve the High-Voltage electrical configuration of the CRP :
lower the 0,5 G Ω quenching resistors & introduce a drain C between LEM & Grid.

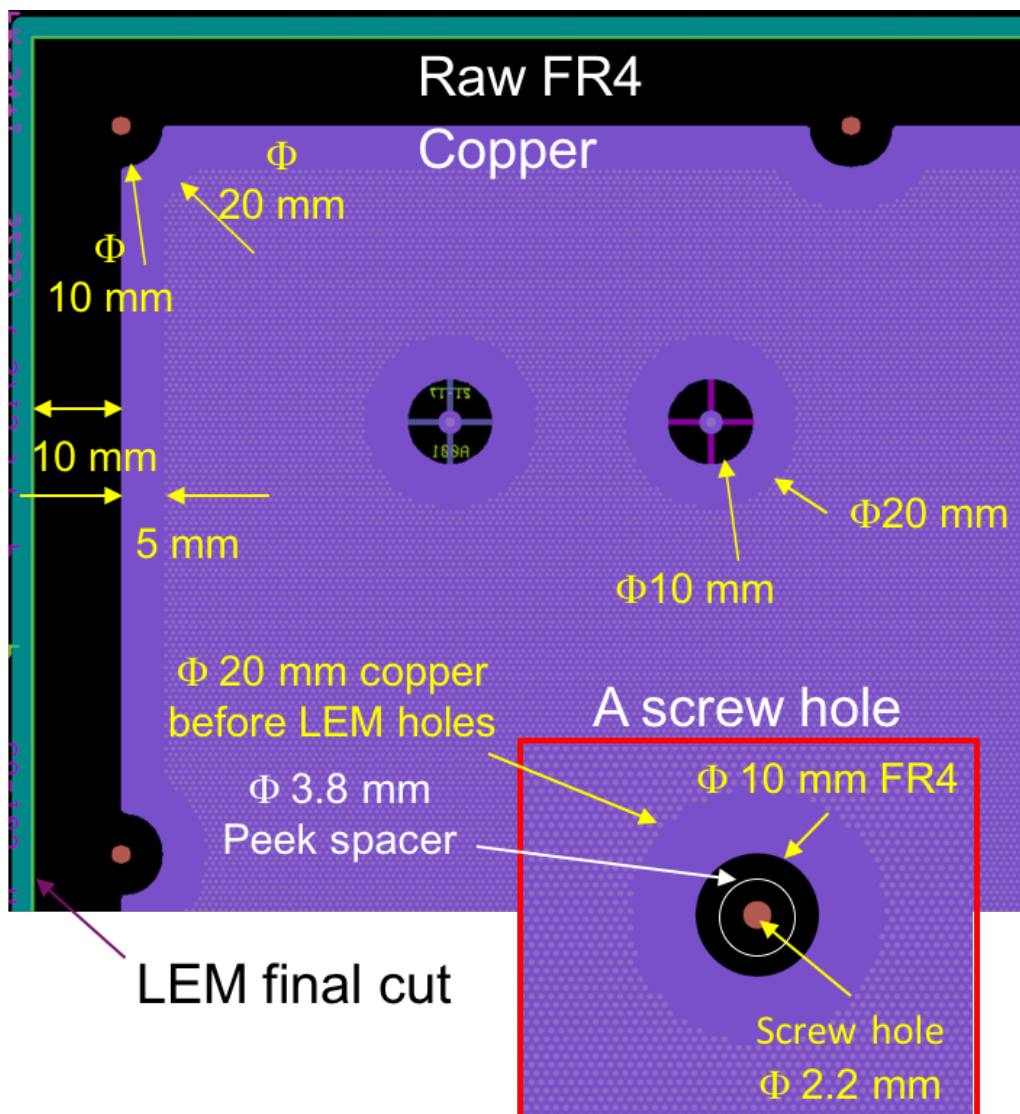


- increase Grid-LEM distance from 10 to 12 mm (decrease C) ?
- add diodes in LEM HV distribution path to lower cross-talks between LEMs ?
- Drain spark charges through grounding dedicated paths
 - Add a guard ring on the anode, connected to a separate ground from FEE
 - Add grounded guard ring on the outer frame of the CRP mechanical structure
 - Use resistive path on grid spacers to collect positive ions stuck on LAr surface ?
- Other CRP design modifications (to discuss at tomorrow's session)

Towards ProtoDUNE-DP phase II

LEM design

CFR-35 – NP02



from modified CFR-35 + pyralux design

« secured design » (dvpt time / production)

- FR4 border decrease : 10 \searrow \sim 2 mm
- Copper border : 5 \searrow \sim 2 mm
- Pyralux covering of copper borders
- Φ 0,5 \uparrow Φ 0,6 mm LEM holes on borders ?
- Segmentation ?
- + LEM-Grid HV distribution modification
- + adding a guard ring on anode PCB

Longer time scale developments (>2022)

- Resistive LEM (DLC or else)
- Soldermask rings on RIMs
- New ideas for charge readout in DLAr



Backup slides for discussion

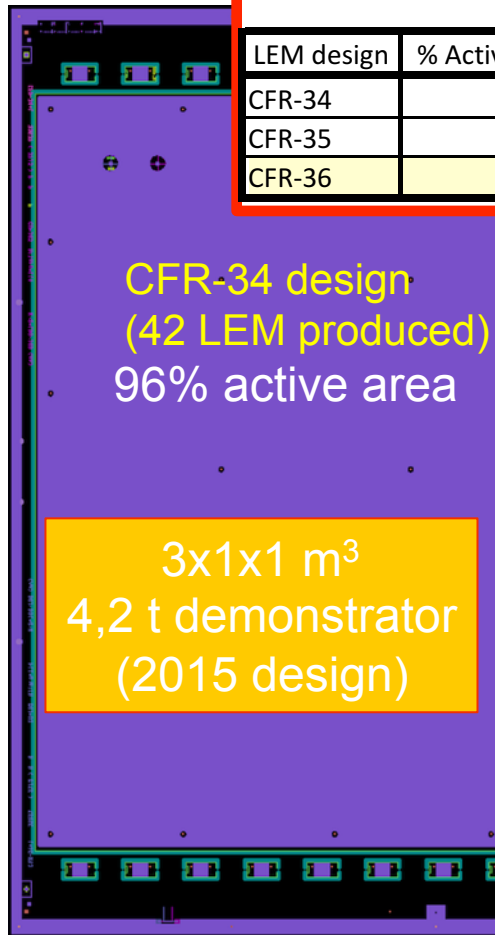
LEM performances

- ✓ Observation of spark rate dependence on collection electric field
 - secondary sparks in induction gap ? How to mitigate this effect ?
 - need of Electric field simulations for further optimization
- ✓ Positive ions feedback and accumulation on LAr surface ?
- ✓ LEM ageing but no hint of resistive current between LEM sides ?
- ✓ LEM – Grid capacitive coupling depending on LAr stability
 - The quenching resistor does not affect LEM & grid the same way
 - Introduction of a coupling capacitance between LEM & Grid ?
- ✓ Explanations for 2 times lower gain derivation from cosmic tracks deposition compared to extrapolation of 3L ETHZ DLAr gain ?

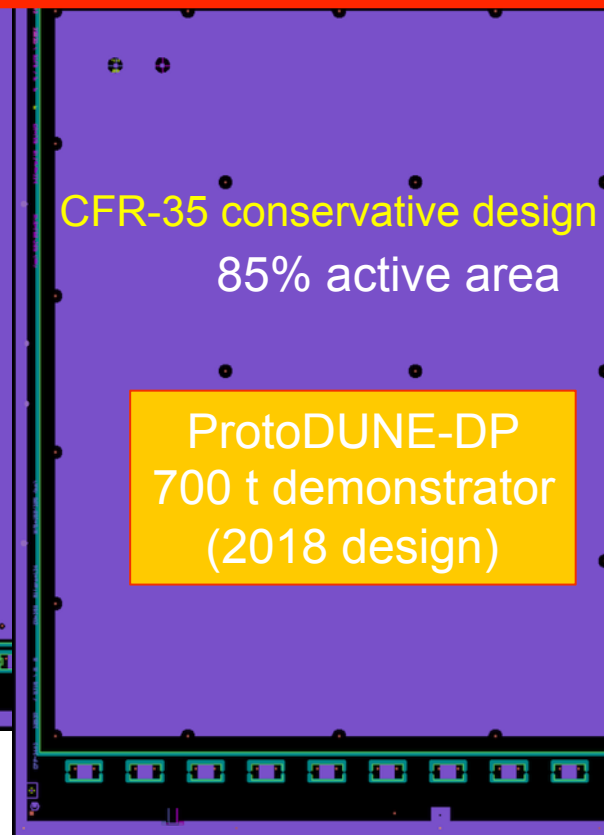
History of LEM designs

LEM design	% Active area	LEM borders		Screw holes		HV connections	
		FR4	copper guard ring	FR4 ring Φ	copper guard ring Φ	FR4 ring Φ	copper guard ring Φ
CFR-34	96.2	2 mm	2 mm	4.2 mm	6 mm	10 mm	12 mm
CFR-35	85.8	10 mm	5 mm	10 mm	20 mm	10 mm	20 mm
CFR-36	92.1	2 mm	5 mm	10 mm	20 mm	10 mm	20 mm

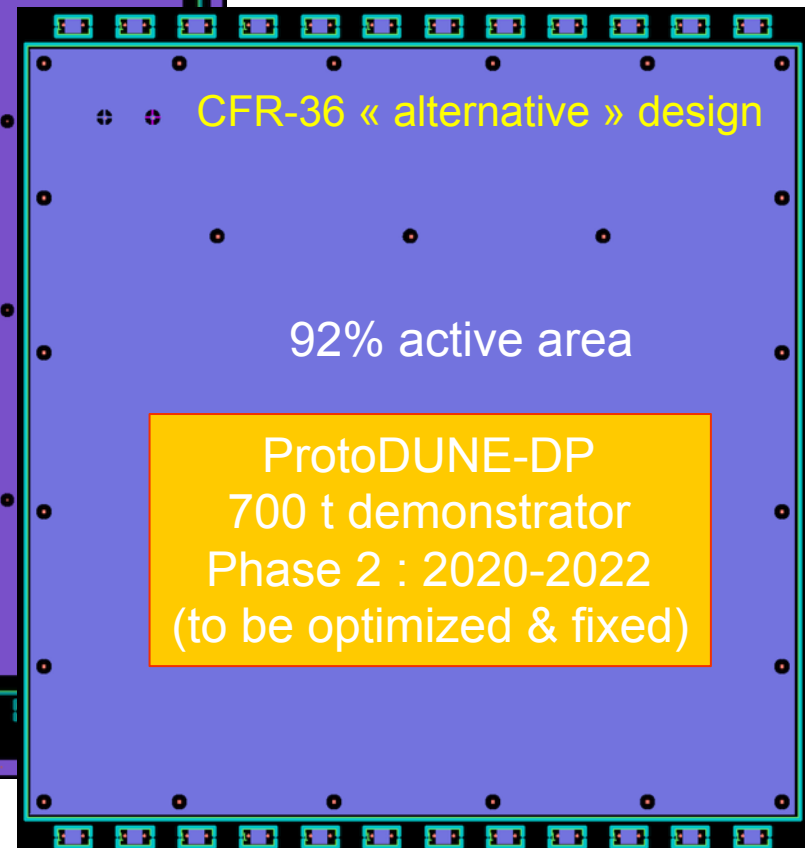
?



2015-2017



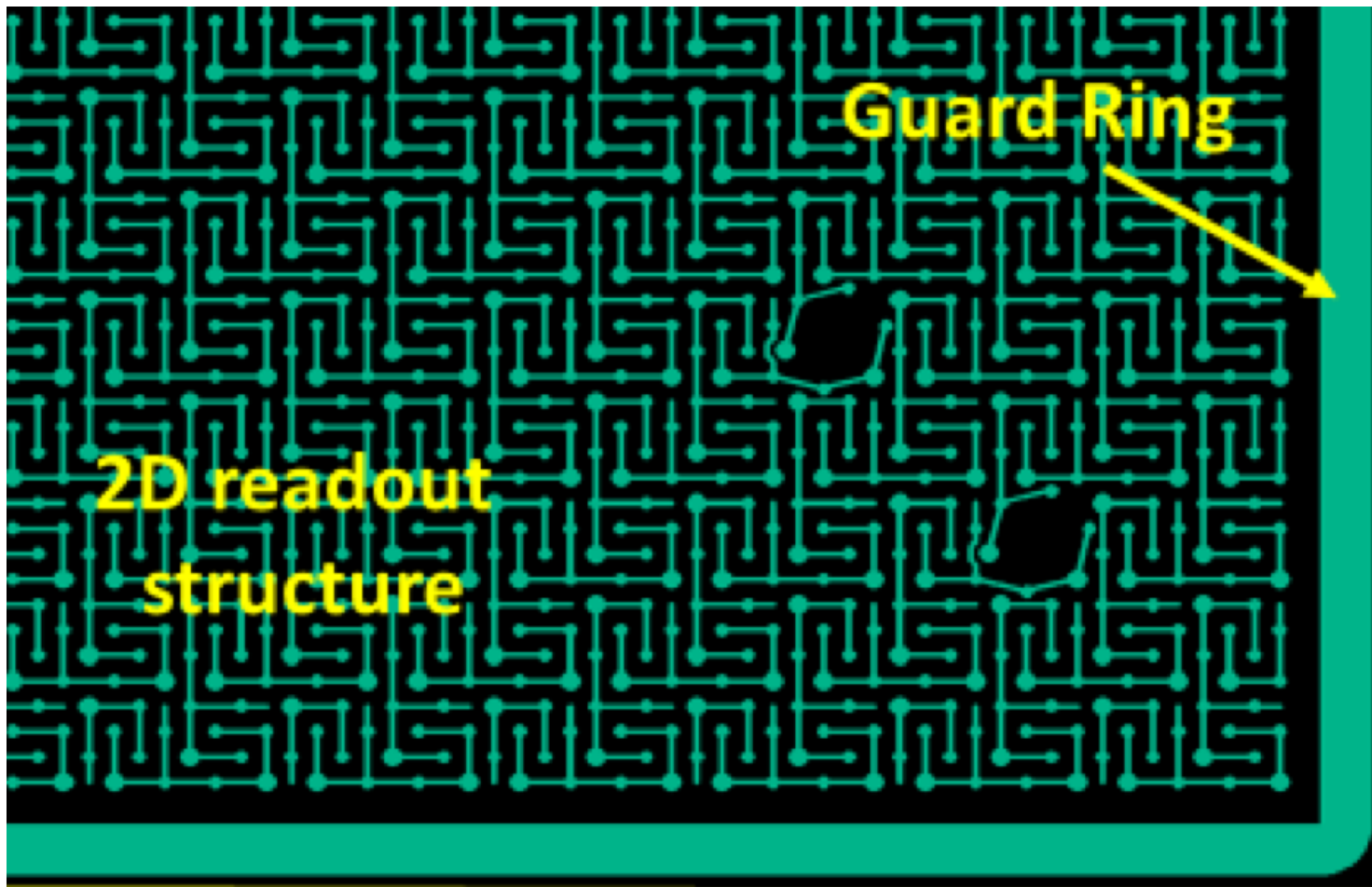
2018-2020



2020-2022 → DUNE FAR ?

Anode guard ring

- New design with a guard ring on both faces of the PCB (**3 mm < LEM dead zone**)
- to mitigate risks associated with sparks causing damages to the FE electronics
- 2 prototypes will be ordered to PCB industrial partners ELTOS (it.) and ELVIA (Fr.).



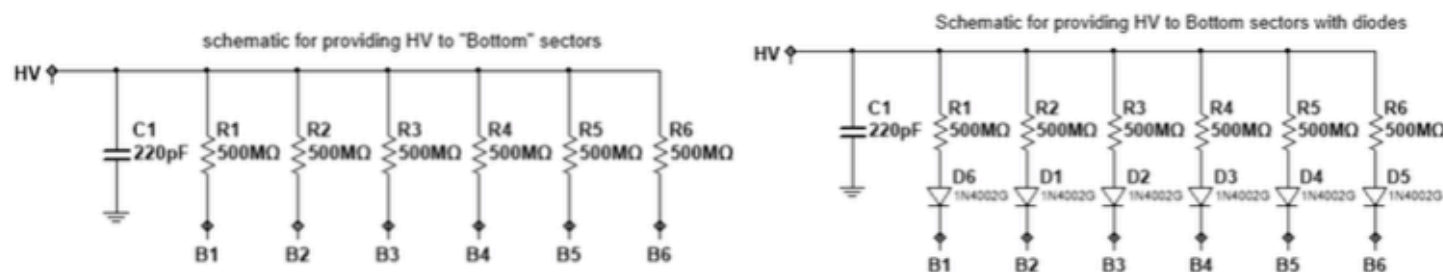
INFN/COMPAS-RICH THGEM

HV distribution

HV distribution to the THGEM, the issue of discharge propagation between sectors, a possible wayout

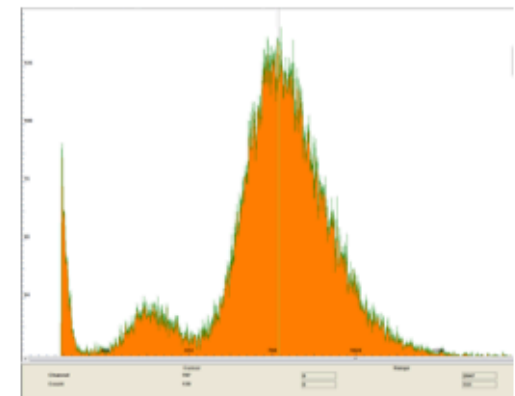
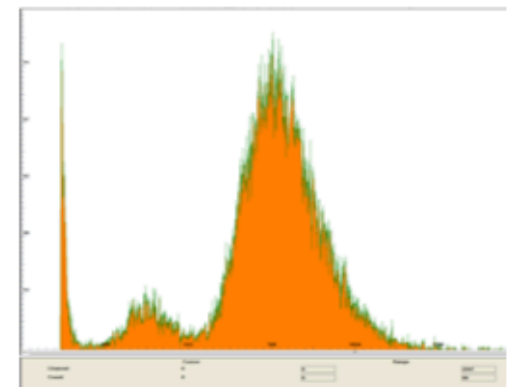


Discharge effect propagation from one sector to others (also non adjacent ones!) lowering voltage and reducing the neighboring sectors efficiency
HV distribution suspected.



Collect spectra on one sector before and after a trip occurs in another sector (induced)
Comparison of the two spectra just before and after a trip in next to it sector.

Analogous scheme also
for the top
Diode: VS-20ETS High Voltage, Input Rectifier Diode



CFR-34 & CFR-35 (ELTOS)

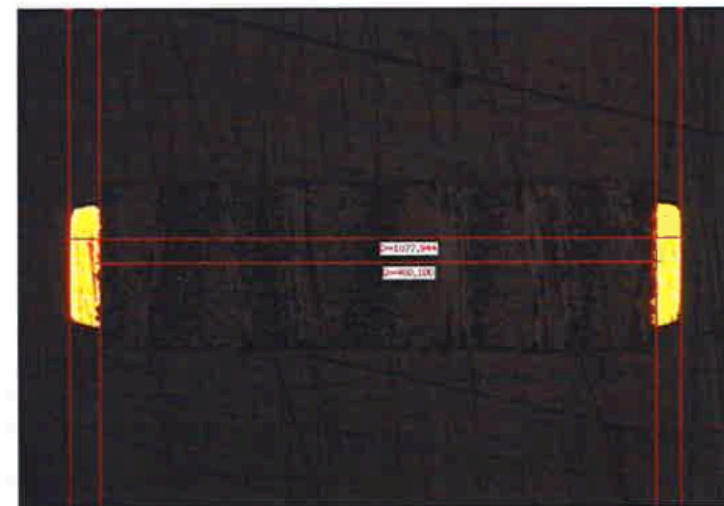
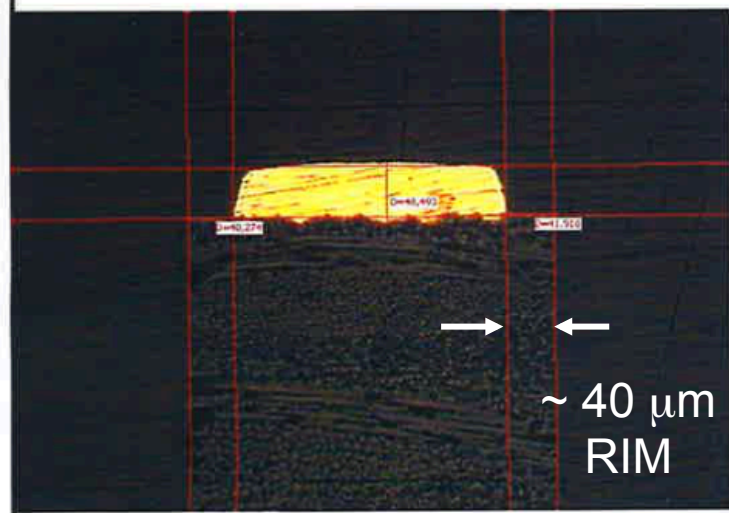
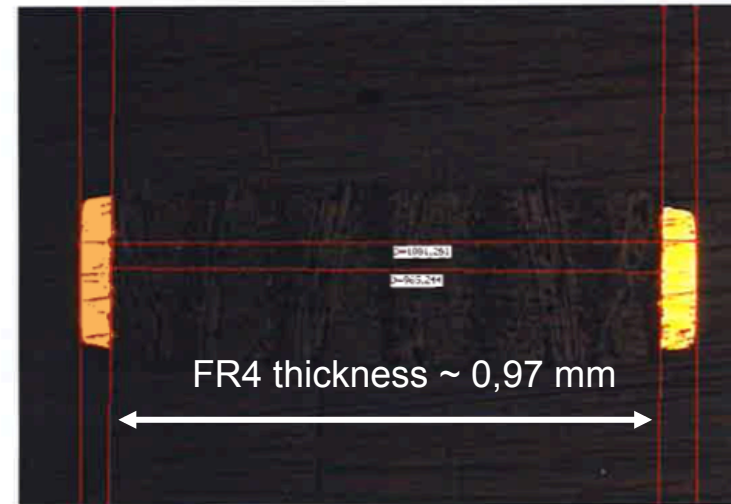
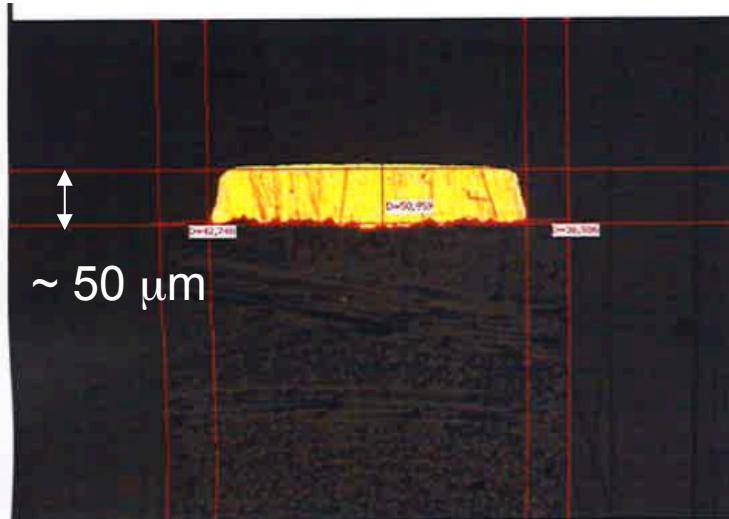
Common specifications

Laminate specifications	
Laminate	FR4 epoxy PANASONIC R-1566W
Dimensions	530 mm x 540 mm
Bare FR4 epoxy thickness	1 mm (-0.05 /+0 mm) Meas. 0,98 mm
Copper thickness	105 μm
Mean thickness	1,20 (-0.06/+0) mm
Thickness uniformity	+/- 0.04 mm
final LEM specifications	
Dimensions	499.5 mm x 499.5 mm +0/-0.3 mm
Ni/Au	5 μm Ni + 0.1 μm Au Meas. +0,003 mm
Final thickness	1.10 (-0.05/+0.02) mm Meas. : 1,11-1,12 mm
LEM holes	\approx 400 000 non-plated $\Phi=0.5$ mm -0/+0.01 mm
RIM (with Ni/Au)	40 μm +/- 4 μm Meas. : 37 - 42 μm

CFR-35 metallographic sections

Standard RIM global etching

metallographic sections : 1.07 mm total thickness ($\sim 0,97$ FR4 + $0,1$ copper+Ni/Au)

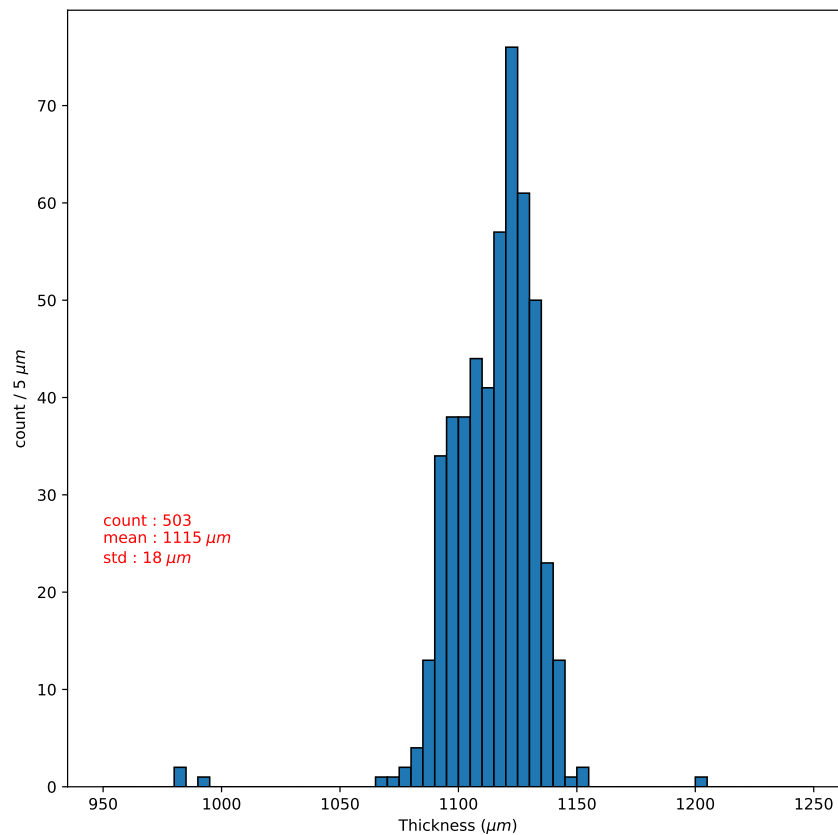


LEM thickness measurement @ Saclay

Ph. Cotte PhD defense, sept 2019

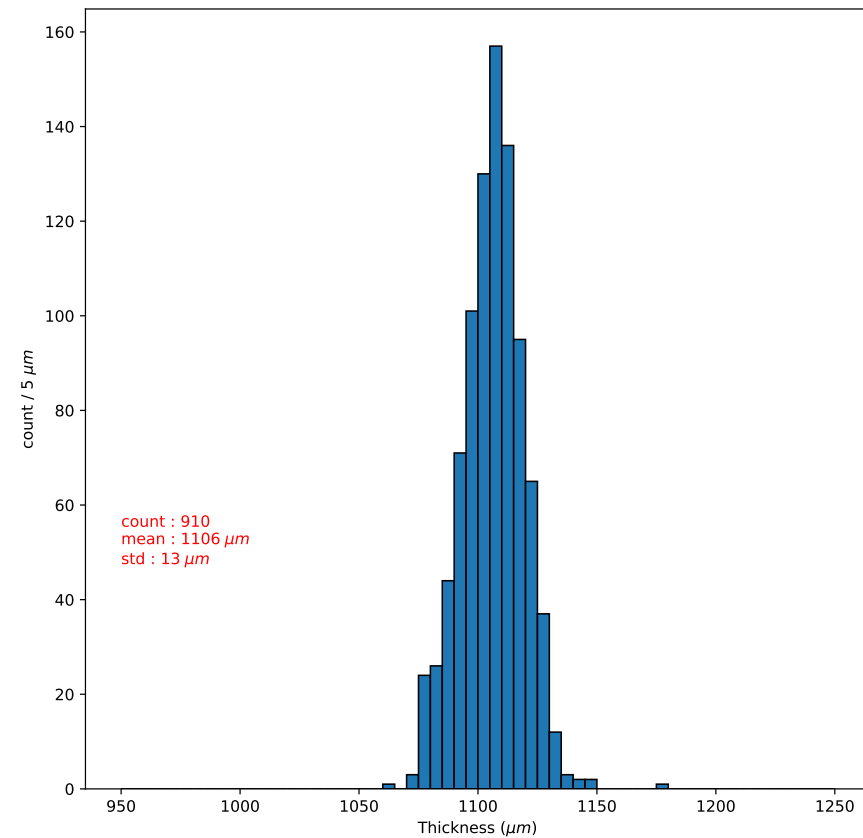
CRP#1 LEMs

Mean LEM thickness : 1.115 mm



CRP#2 LEMs

Mean LEM thickness : 1.106 mm

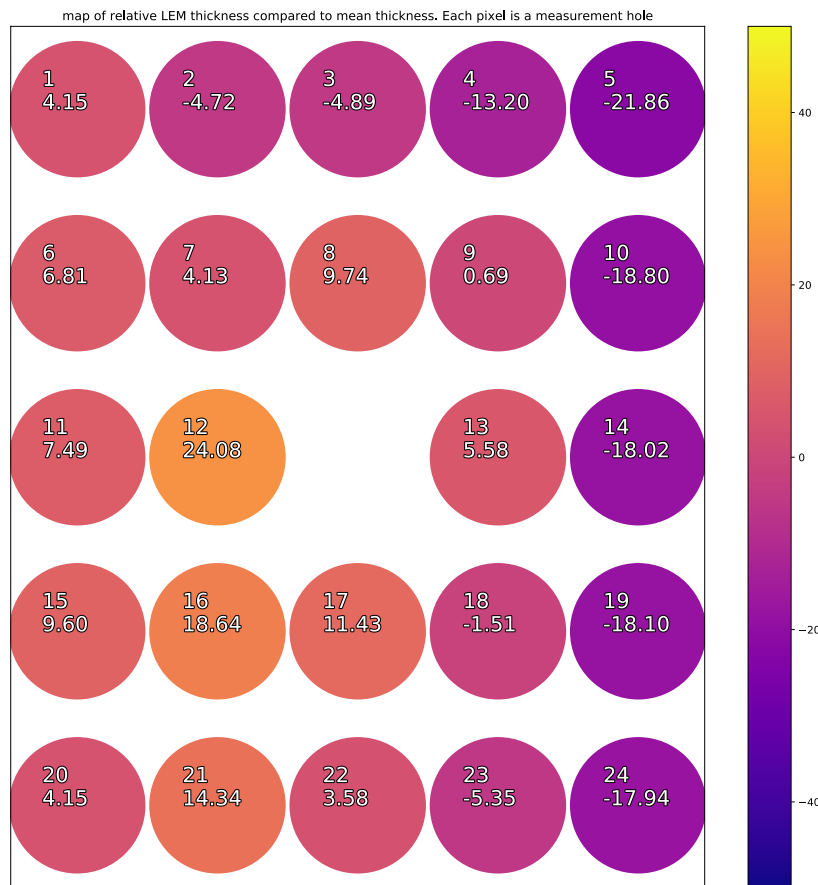


Specification : 1,10 mm -0,05/+0,02 mm

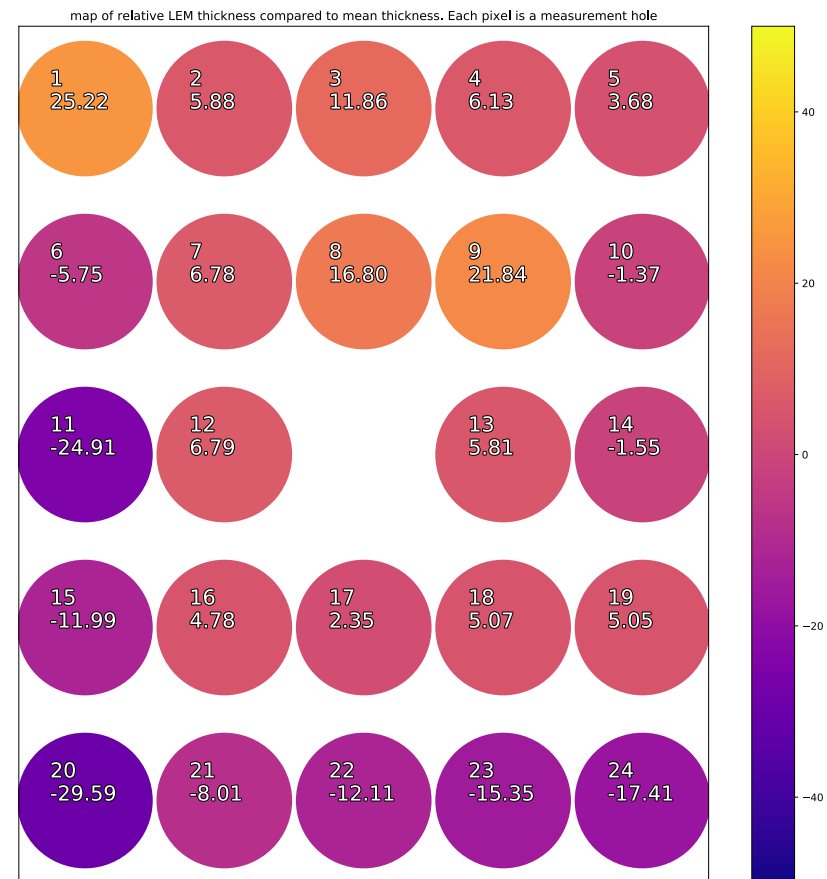
LEM thickness measurements @ Saclay : uniformity over LEM surface

Ph. Cotte PhD defense, sept 2019

LEM CRP#1/A081 Mean thickness : 1,112 mm
+ 24 μm / - 22 μm



LEM CRP#2/A120 Mean thickness : 1,111 mm
+ 25 μm / - 30 μm

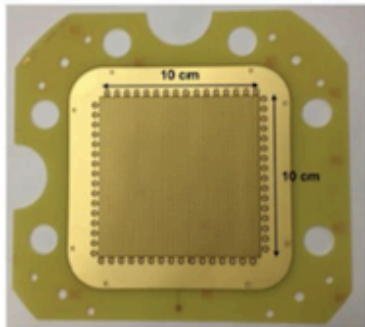


10x10 LEM sparking

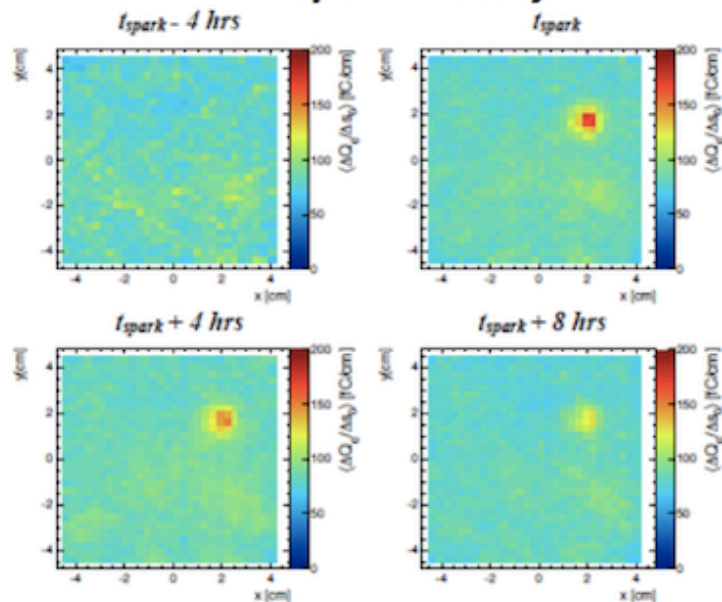
LEM charging up, sparks and long-term performance

C. Cantini et al., arXiv:1312.6487

**ETHZ 10x10
prototype**

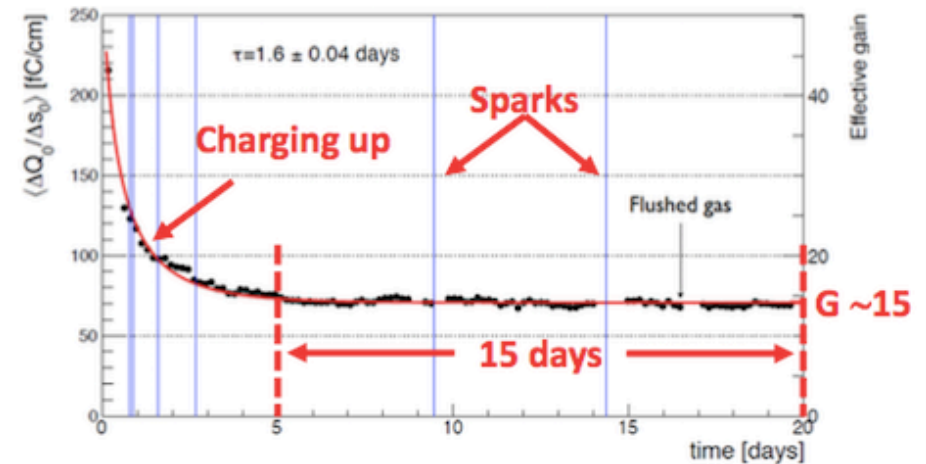


LEM spark history



**LEM charging up destroyed
locally ($\sim \text{cm}^2$) after a spark**

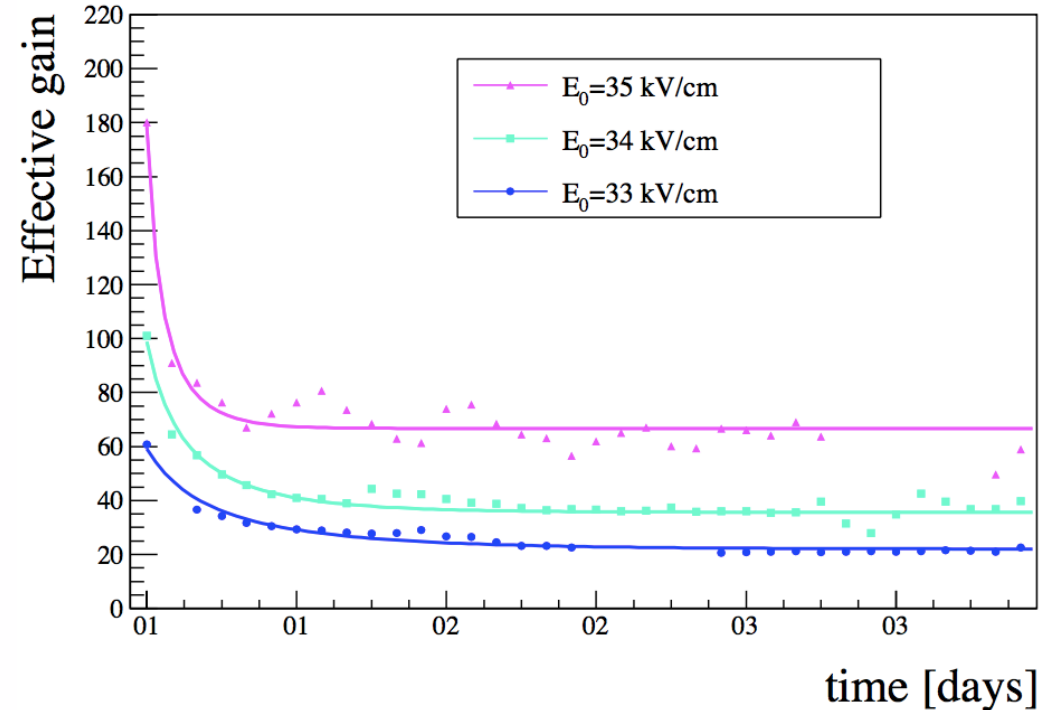
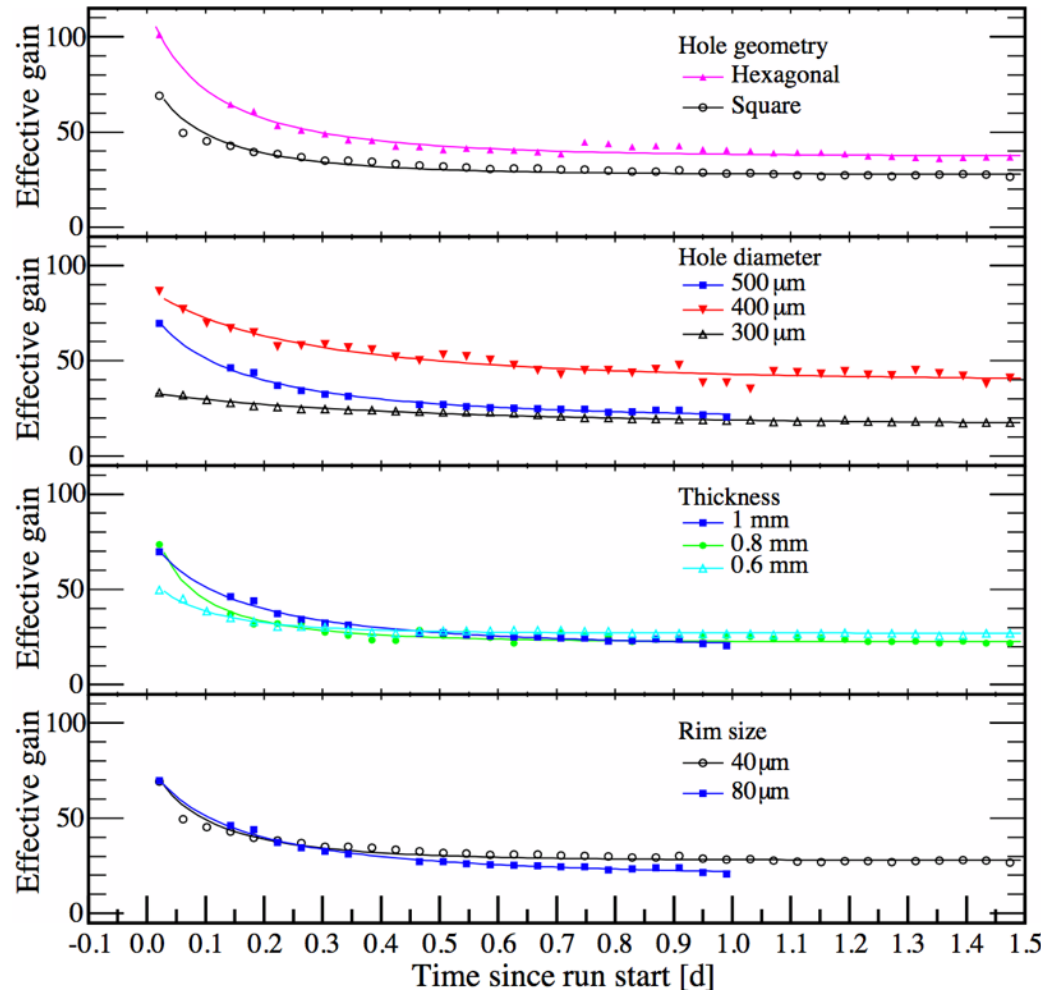
**LEM dielectric charging up due to
E-field lines crossing walls around holes**



- 2 sparks in 15 days after charging up
- Extrapolation to 3m×3m :
(5.0 ± 3.5) sparks/h @ $G \sim 15$

LEM charging-up

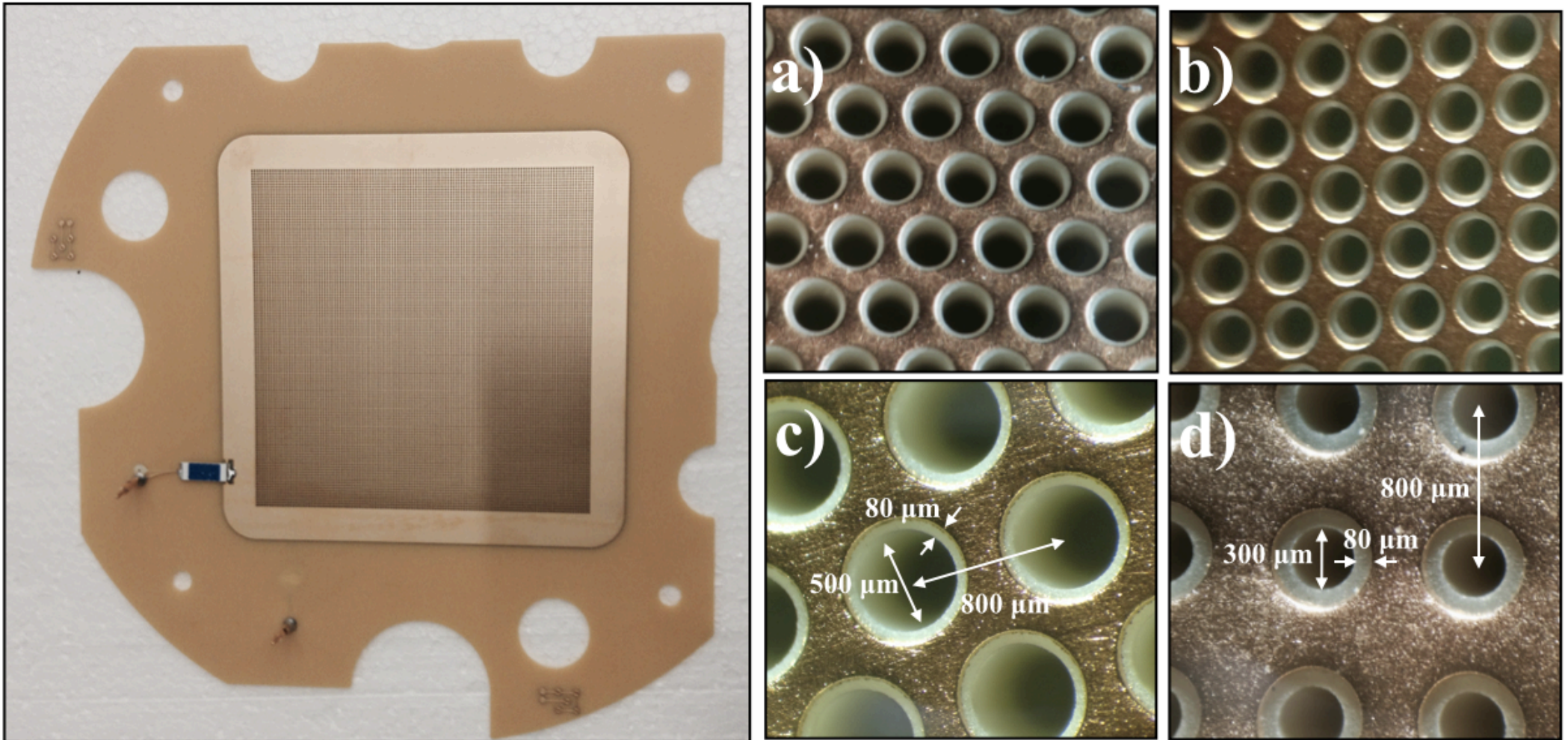
C. Cantini et. Al, JINST **10** (2015)



Charging-up effect on gain drop value & time behaviour depends on amount of FR4 material :
RIM size, hole diameter, LEM thickness, density of holes
measured ~ 3.3 in 2-3 h for ProtoDUNE-DP LEMs at Saclay with ^{251}Am α source

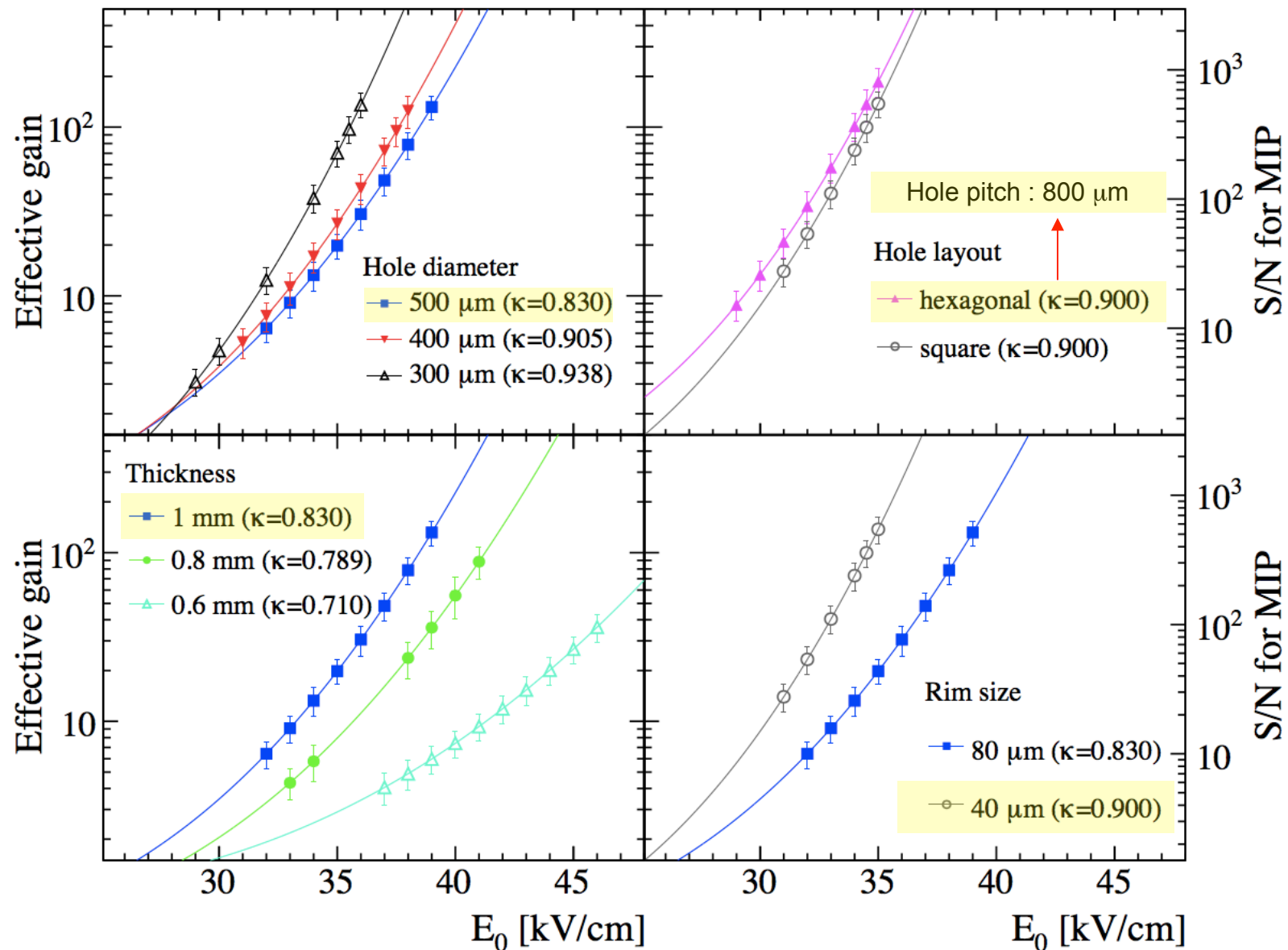
LEM holes modifications ?

10x10 cm² with large FR4 border



C. Cantini et. Al, « Performance study of the effective gain of the double phase liquid Argon LEM Time Projection Chamber, JINST **10** (2015)

LEM key parameters



C. Cantini et. Al, « Performance study of the effective gain of the double phase liquid Argon LEM Time Projection Chamber, JINST **10** (2015)

Alain Delbart, R&D on LEM for phase II of ProtoDUNE-DP, LEM, Workshop on the LEM/Thick GEM cryogenic utilization in pure Argon over large detection surfaces, 6-7th april, 2020

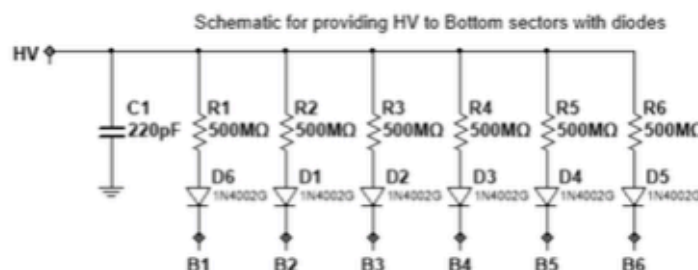
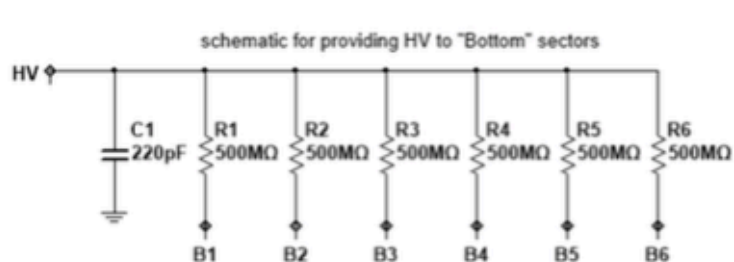
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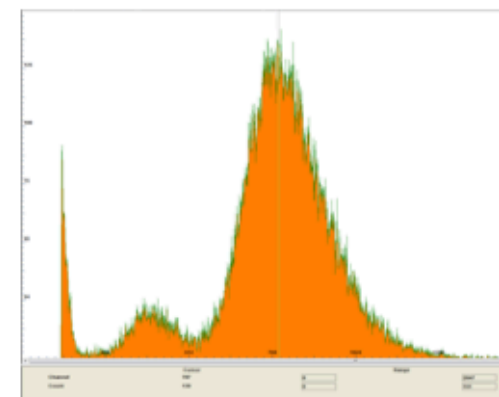
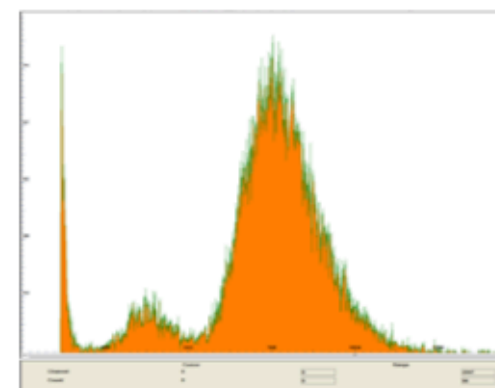
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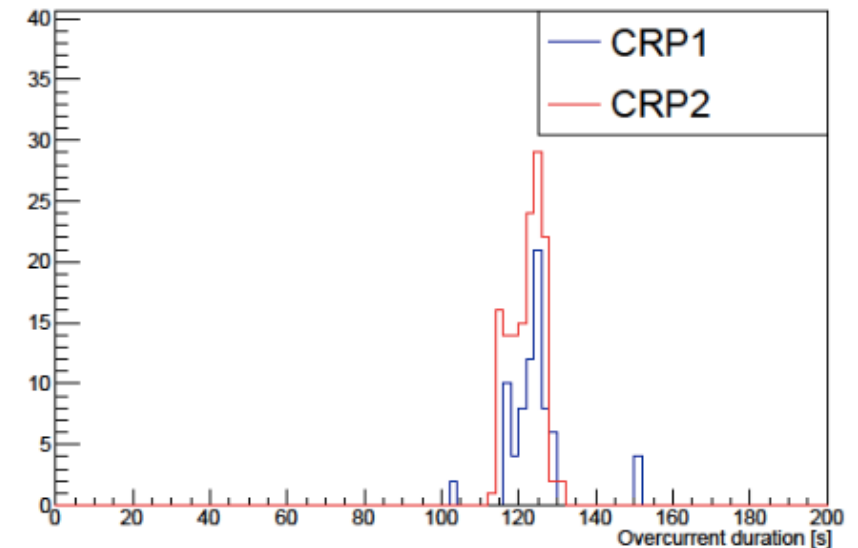
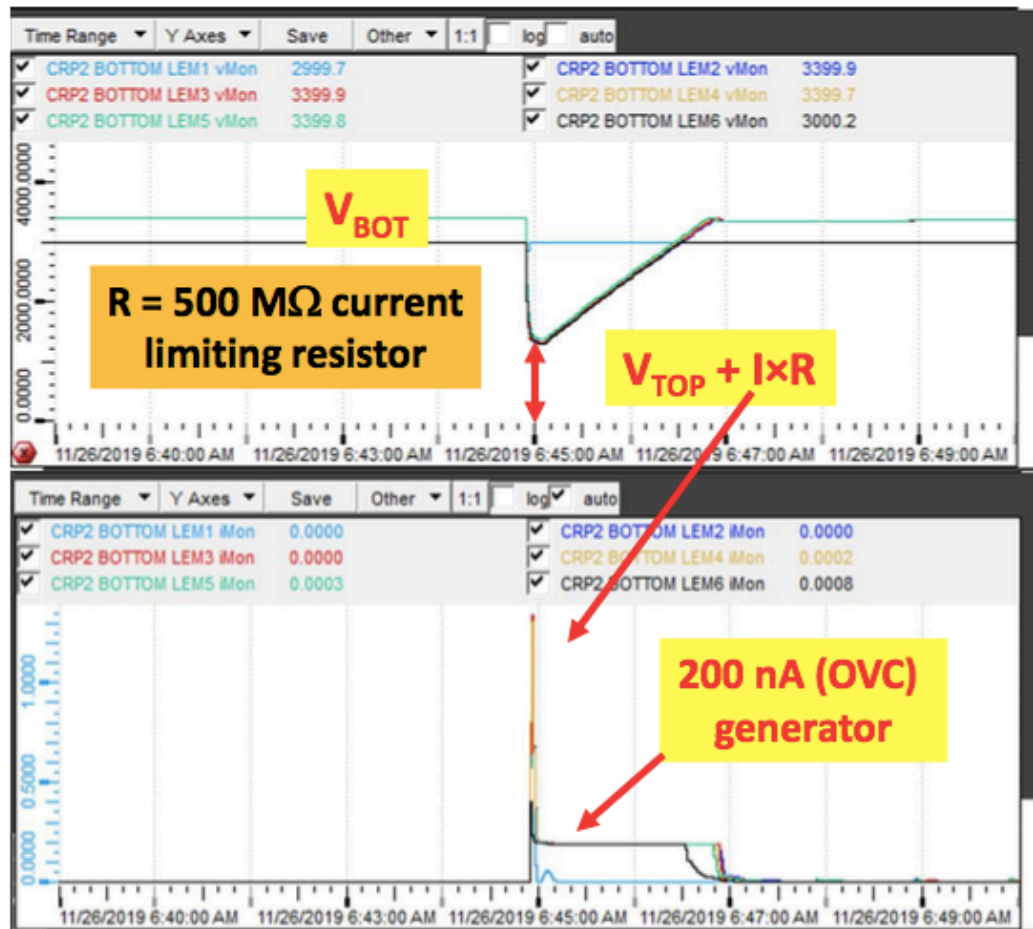
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ProtoDUNE-DP

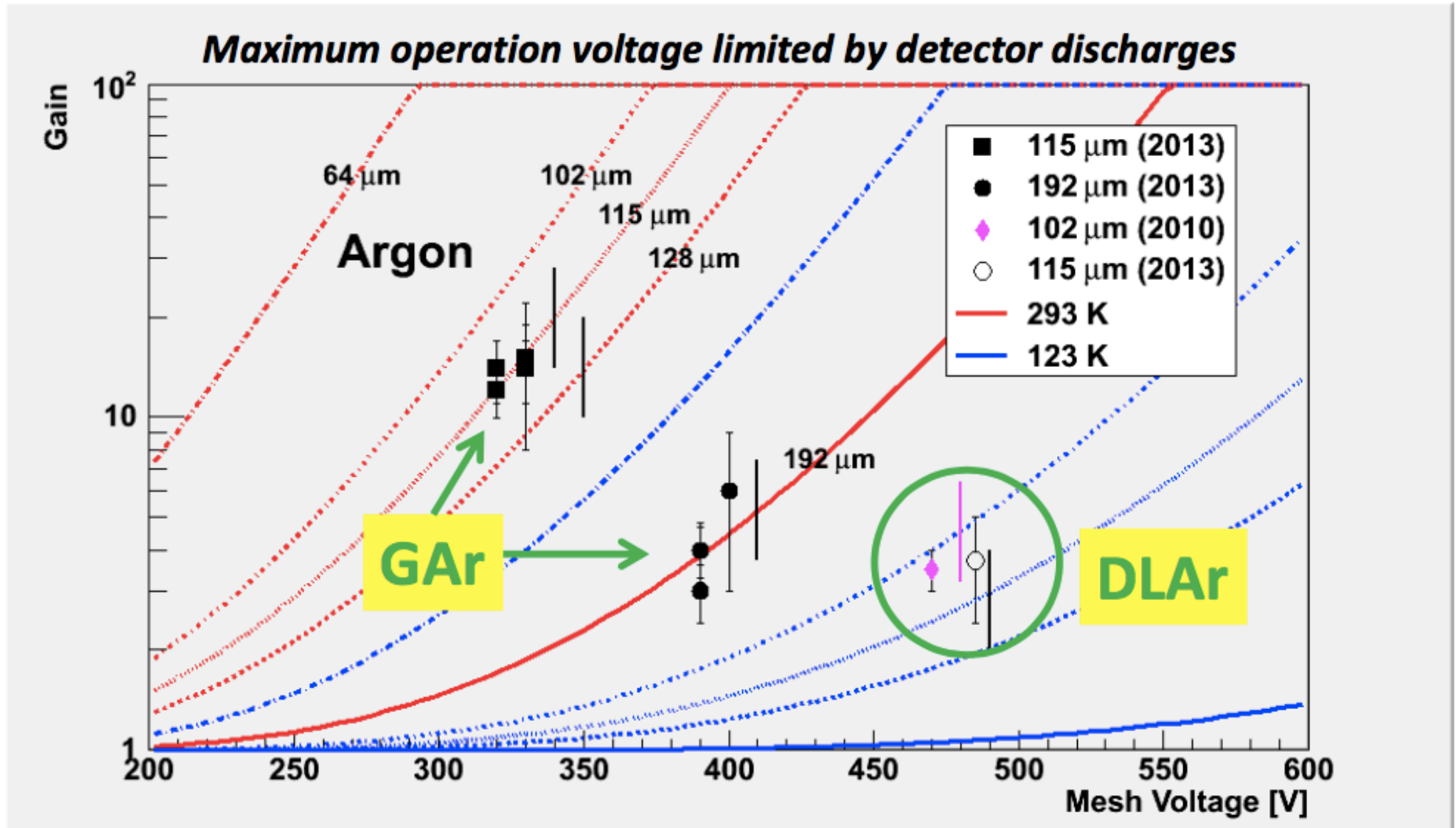
LEM HV slow-control



Dead time due to a LEM spark is set to 2 minutes. Not an issue for rates at the level of a several sparks per hour and per CRP.

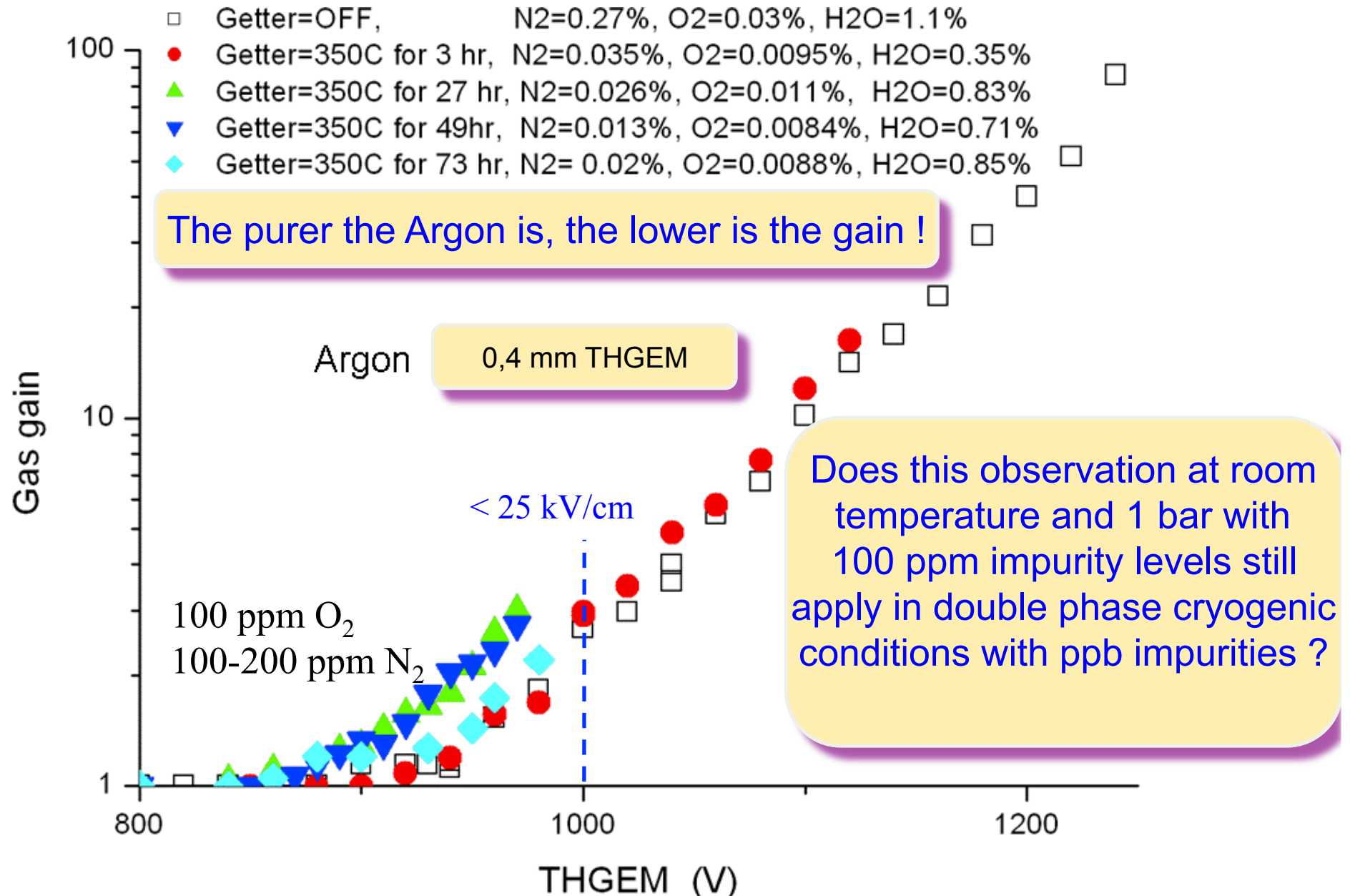
Micromegas for Dual phase Lar-TPC ?

$$G \sim e^{\alpha(p,T,V)d} \text{ with } \alpha = (Ap/T)e^{-Bpd/VT}$$



E. Mazzucato, WA105 kick-off meeting, CERN, october 15-17, 2014

Gain limits in pure Argon : a possible explanation ?



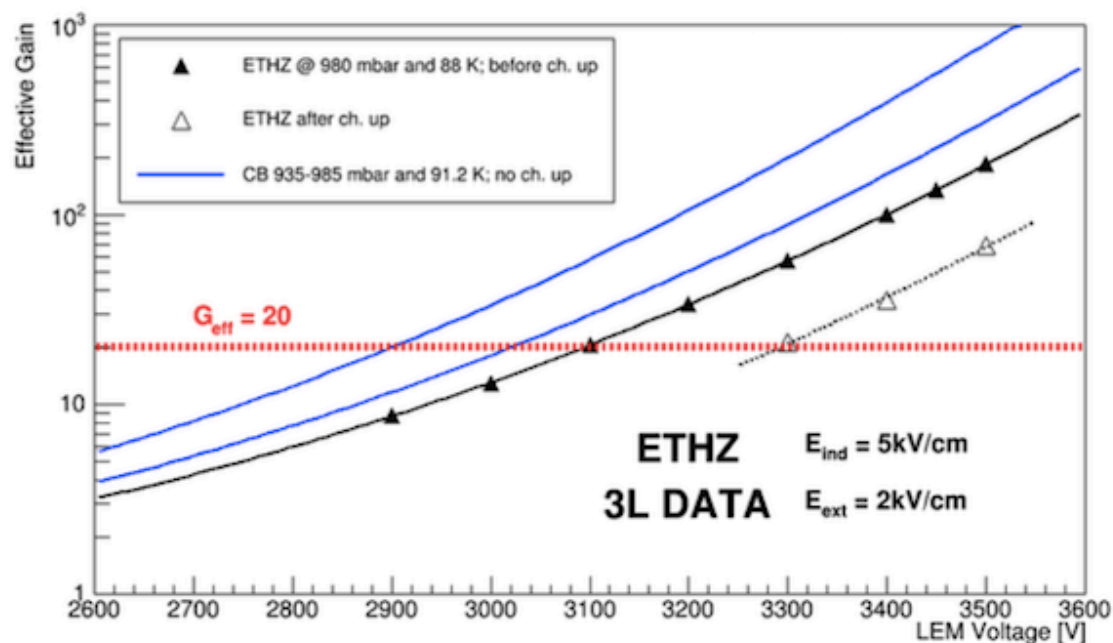
Ref: J. Miyamoto, A. Breskin and V. Peskov, JINST 2010, doi:10.1088/1748-0221/5/05/P05008

Effective gain

Effective gain

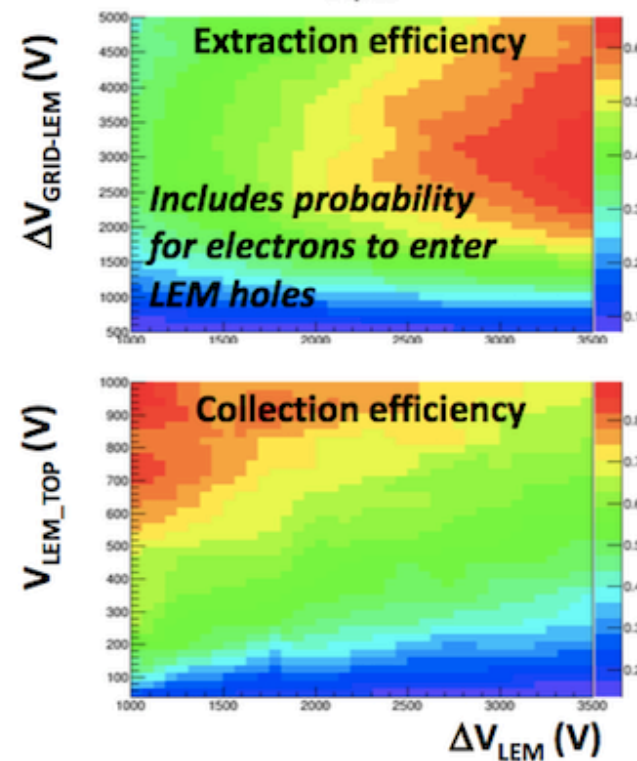
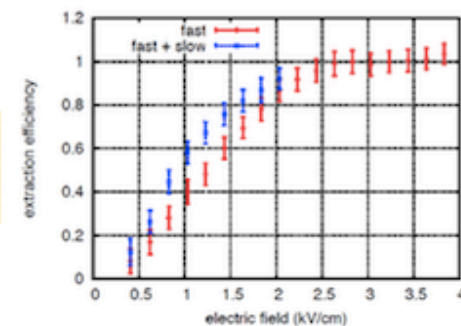
Gushchin et al., Sov. Phys. JETP 55 (1982) 860-862.

$$G_{\text{eff}} = \varepsilon_{\text{extr}} \times G_{\text{LEM}} \times \varepsilon_{\text{ind}}$$



06/04/2020

Workshop on the LEM/Thick GEM cryogenic utilization in pure Argon over large detection surfaces



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